



Atty. Docket No.: A-69175-1/ MSS
Client/Matter No.: 463035-650

3723.8
AF/61

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Nam P. Suh et al.

Serial No.: **10/029,158**

Filed: **December 21, 2001**

For: **APPARATUS AND METHOD FOR
CHEMICAL MECHANICAL
POLISHING OF SUBSTRATES**

Examiner: **RACHUBA, Maurina T.**

Art Unit: **3723**

San Francisco, CA 94111

Date: **September 13, 2004**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RECEIVED
SEP 21 2004
TECHNOLOGY CENTER 3700

AMENDMENT/RESPONSE

Sir:

In response to the Office Action mailed April 13, 2004, Applicants submit the following amendments and remarks accompanied by a Petition for Extension of Time under 37 CFR 1.136(a) with proper fees, extending the period for response by two (2) month.

Amendments to the Specification begin on page 2 of this paper

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.

Amendments to the Drawings begin on page 10 of this paper.

Remarks/Arguments begin on page 11 of this paper.

09/17/2004 DEMMANU1 00000025 10029158

01 FC:1202

144.00 OP